

ABSTRACT OF THE DISCLOSURE

A production apparatus having a small footprint and a method of producing a light-emitting device by using the production apparatus. The apparatus for producing light-emitting devices, comprises a loading chamber, a chamber for forming a film of a light-emitting material, a chamber for forming a film of an electrically conducting material, a chamber for forming a film of an insulating material and an unloading chamber, wherein the chamber for forming the film of the light-emitting material is the one for forming the film of the light-emitting material by a liquid jet method, the chamber for forming the film of the electrically conducting material is the one for forming the film of the electrically conducting material by a sputtering method, and the chamber for forming the film of the insulating material is the one for forming the film of the insulating material by the sputtering method, and wherein a substrate to be treated is so supported that an angle subtended by the film-forming surface of the substrate to be treated and the direction of gravity is within from 0 to 30° in all of the loading chamber, the chamber for forming the film of the light-emitting material, the chamber for forming the film of the electrically conducting material, the chamber for forming the film of the insulating material and the unloading chamber.